



# SEMIPROBE®

Test • Inspect • Innovate

## SUCCESSFUL APPLICATION: MEMS - 0721



### Specific Requirements:

A customer required a turnkey and integrated wafer probing system to test up to 200 mm microfluidic MEMS wafers, partial wafers, and individual die over temperature. The integrated solution had to provide a fully functional probing and high magnification inspection capabilities using one platform. Programmable manipulators would be used for electrical testing and fluidic dispense. The devices needed to be heated and monitored from ambient to over 300 °C.

### SemiProbe Solution:

- PS4L SA-8 Semi-automatic 200 mm probe system:
  - 200 mm programmable X, Y, Z and theta stage
  - Vibration isolation table
  - Customized GUI
- Thermal chuck system that operates up to over 300 °C
- Custom carriers for whole wafers, partial wafers, and individual die
- Microfluidic Dispense System – input and output
- Four programmable X, Y, Z manipulators with coaxial, triaxial and high frequency probe arms
- Probe card holder
- Dark box and dark box feedthrough interconnect panel
- Test instrumentation rack and cabling